

1 **Electronic Supplementary Information**

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3 **Bio-inspired, Sensitivity-enhanced, Bi-directional Airflow Sensor**  
4 **for Turbulence Detection**

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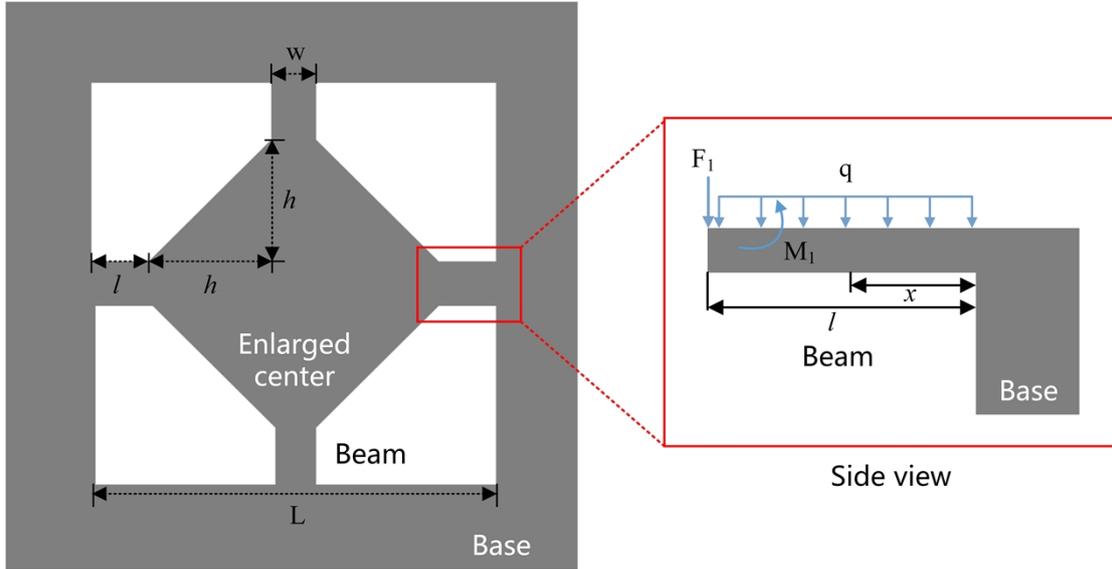
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1 **Supporting information S1:**

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4 **Figure S1.** The geometrical dimensions of the cruciform beam with an enlarged center,  
5 and the side view of the beam under airflow pressure.

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7 The external stimulus such as wind pressure led to beam deflection and induced stress  
8 inside the beam. To analyze the effect of the enlarged center of the cruciform beam, we  
9 built a theoretical model of the cruciform beam with an enlarged center under the flow  
10 field. The parameters of the cruciform beam with an enlarged center are shown on the  
11 left of Fig. S1. The center of the cruciform is enlarged by complementing the center  
12 corners with isosceles right triangles. The relationship between the length of the center  
13 opening  $L$ , the width of the cruciform beam  $w$ , the length of the right-angled side of  
14 central right triangles  $h$ , and the length of the beam  $l$  satisfies equation 1:

15 
$$L = w + 2 * (l + h) \tag{1}$$

16 When air flows through the cruciform beam from the front, the schematic diagram  
17 of the forces on the beams is shown on the right of Fig. S1. Three loads appear on the  
18 beam: the wind pressure  $q$  applied on the beam, force  $F_1$  produced by the enlarged  
19 center under wind pressure and averaged by four beams, and torque  $M_1$  caused by the  
20 bending deformation of the enlarged center. The force  $F_1$ , which relates to the area of

1 the enlarged center, can be calculated by averaging the total force with four beams as  
 2 equation 2:

$$3 \quad F_1 = \frac{1}{4}q(2h^2 + 4hw + w^2) \quad (2)$$

4 The torque  $M_l$  on the beam at the position  $x$  away from the base can be defined as  
 5 equation 3:

$$6 \quad M_l = M_1 - F_1(l - x) - \frac{qw(l - x)^2}{2} \quad (3)$$

7 The bending angle  $\theta_l$  caused by the torque at position  $x$  on the beam can be obtained  
 8 by integrating the torque as equation 4:

$$9 \quad \theta_l(x) = \int_0^x \frac{M_l(x)}{E_b I_{bz}} dx + C \quad (4)$$

10 Where,  $E_b$  is the elastic modulus of the beam, and  $C$  is a constant.  $I_{bz}$  is the moment of  
 11 inertias of the beam along the Z direction, and is defined as equation 5:

$$12 \quad I_{bz} = \frac{1}{12}wt^3 \quad (5)$$

13 Where  $t$  is the thickness of the beam. The deflection of the beam  $W_l$  at the position  $x$   
 14 on the beam can be calculated by integrating the bending angle as equation 6:

$$15 \quad W_l(x) = \int_0^x \theta_l(x) dx + Cx + D \quad (6)$$

16 Where  $D$  is a constant. The values of  $C$  and  $D$  can be obtained by plugging the boundary  
 17 conditions into the formula. When the value of  $x$  is zero, which is the joint of the beam  
 18 and base, the values of the bending angle  $\theta_l$  and deflection of the beam  $W_l$  are zero.  
 19 Thus, the constants  $C$  and  $D$  are both 0. When considering the position of the end of the  
 20 beam, the bending angle  $\theta_l$  is zero. Then we get the torque  $M_1$  as demonstrated in  
 21 equation 7:

$$22 \quad M_1 = \frac{1}{24}(6qlh^2 + 3qlw^2 + 4qwl^2 + 12qlhw) \quad (7)$$

1 The deflection of the beam  $W_l$  can be obtained when substituting  $M_1$  into the equations  
 2 and shown in equation 8:

$$3 \quad M_l(x) = \frac{1}{24} \left( \begin{array}{l} -12qwx^2 + 12qh^2x + 24qhw x + 6qw^2x \\ + 24qlwx - 6qlh^2 - 12qlhw - 3qlw^2 - 8qwl^2 \end{array} \right) \quad (8)$$

4 The longitudinal stress  $\delta_l$  can be determined by equation 9:

$$5 \quad \delta_l = - \frac{M_l(x)}{W} \quad (9)$$

6 Where  $W_z$  is the section modulus in Z direction bending and shown in equation 10:

$$7 \quad W_z = \frac{1}{6} wt^2 \quad (10)$$

8 Then the longitudinal stress  $\delta_l$  can be calculated by equation 11:

$$9 \quad \delta_l = \frac{1}{4wt^2} \left[ \begin{array}{l} 12qwx^2 - (12qh^2 + 6qw^2 + 24qhw + 24qlw)x \\ + 6qlh^2 + 3qlw^2 + 8qwl^2 + 12qlhw \end{array} \right] \quad (11)$$

10 When the air flows from the back of the cruciform beam, the direction of the stress and  
 11 bending angle are reversed without changing the calculation method.

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1 **Supporting information S2:**

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3 **Table S1.** The geometrical parameters of the cruciform beam with the enlarged center.

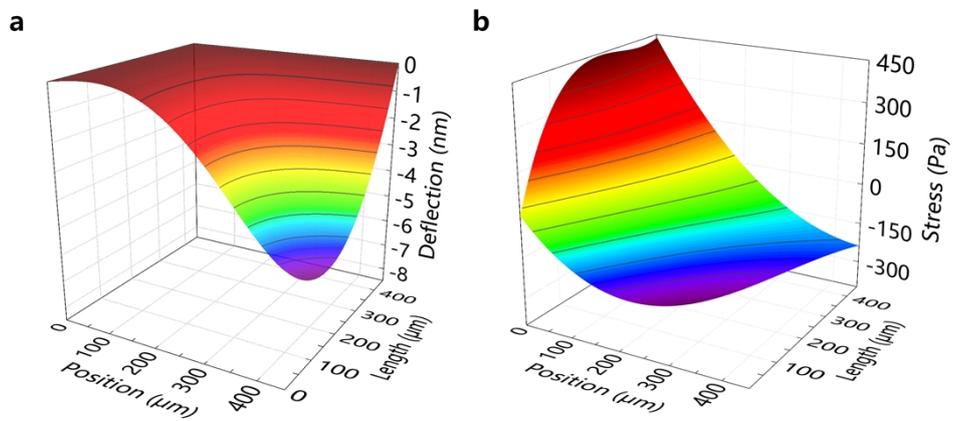
Parameters of the cruciform beam with enlarged center	Parameters
Length of the center opening ( $L$ )	1000 $\mu\text{m}$
Width of the cruciform beam ( $W$ )	100 $\mu\text{m}$
The thickness of the cruciform beam ( $t$ )	50 $\mu\text{m}$
Width of the base	500 $\mu\text{m}$
Length of the base	1000 $\mu\text{m}$
Thickness of the base	450 $\mu\text{m}$
Poisson's ratio	0.23
Young's modulus	160 GPa
Wind pressure	2.5 Pa

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1 **Supporting information S3:**

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4 **Figure S2.** The analysis results of deflection and stress on the whole beam based on the  
5 theoretical models when increasing the length of the beam.

6

7 The external stimulus of airflow pressure led to the surface stress variation and  
8 produced the cruciform beam deflection. We focused on the beam with a concentration  
9 of stress and larger deformation due to the smaller width compared to the enlarged  
10 center. The deflection and stress results based on the theoretical model are shown in  
11 Fig. S2. According to the deflection results, the closer the position of the beam is to the  
12 center, the larger the deflection. The maximum deflection increases and decreases with  
13 the increase of the beam length. This is because the longer the beam, the smaller the  
14 center size and diminished force applied to the cruciform beam. As for the stress results,  
15 the root of the beam is subjected to tensile force with a stress value greater than 0, and  
16 the joint part to the center is subjected to compressive force. The extreme values of  
17 stress appear at the ends of the beam where at the intersection with the base and center.  
18 The maximum stress of 443.8 Pa and minimum stress of -392.65 Pa appear at the root  
19 and end of the beam when the length is 255 and 206 μm, respectively.

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1 **Supporting information S4:**

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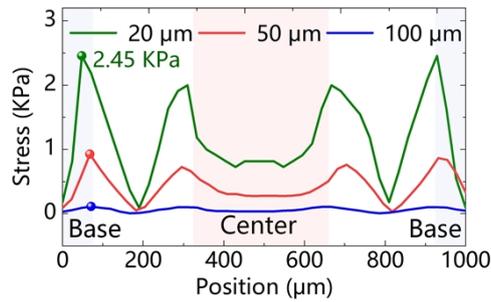
3 The effects of CTS on the center enlarged cruciform beam were analyzed using fluid-  
4 solid coupling models in finite element analysis (FEA) software (ANSYS Workbench  
5 2019). The cruciform beam in this analysis was made of silicon material with Young's  
6 modulus of 160 GPa and Poisson's ratio of 0.23. It was positioned in the center of a  
7 square tube of  $6 \times 6 \times 6 \text{ m}^3$  in size. Flowing air at 2 m/s speed entered the tube inlet while  
8 the pressure at the tube outlet was maintained at 0 Pa. The density, viscosity, and  
9 temperature of the air were set to  $1.225 \text{ Kg/m}^3$ ,  $1.7894 \times 10^{-5} \text{ Kg/m} \cdot \text{s}$ , and 288.16 K,  
10 respectively. The structural element was SOLID186. The bi-directional performance of  
11 the cruciform beam was analyzed by turning it over under a consistent airflow direction.

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1 **Supporting information S5:**

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4 **Figure S3.** The stress distribution on the bioinspired center enlarged cruciform with  
5 various thicknesses (20, 50, and 100 μm).

6 The stress distribution on the bioinspired center enlarged cruciform with various  
7 thicknesses (20, 50, and 100 μm) under the same pressure of 2.5 Pa is shown in Fig.  
8 S3. The results revealed that the stress on the beam is concentrated in the areas where  
9 the beam meets the center and base. As the beam thickness is reduced, the maximum  
10 stress rises from 0.09 to 2.45 KPa. The improved maximum stress value implies an  
11 increased sensitivity of the sensor, but the overly concentrated stress results in a high  
12 fracture risk which reduces the durability. Therefore, to balance the sensitivity and  
13 durability, we determined the thickness of the beam to be 50 μm.

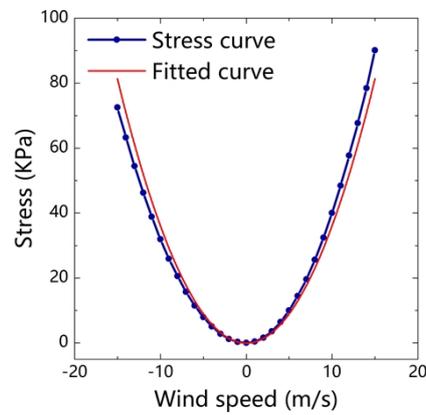
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1 **Supporting information S6:**

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4 **Figure S4.** The maximum stress on the cruciform beam with CTS and enlarged center  
5 when increasing the airflow speed from 0 to  $\pm 15$  m/s by FEA analysis.

6

7 To investigate the response of the cruciform beam with CTS and enlarged center  
8 detecting bi-directional stimuli, we increased the airflow speed from 0 to  $\pm 15$  m/s of  
9 the FEA analysis. The maximum stress, which reflects the distribution of load, on the  
10 structure was collected as shown in Fig. S4. The maximum stress values are highly  
11 fitted to an asymmetry curve with the  $R^2$  of 0.97495, and the equation of the fitted curve  
12 is described in equation 12:

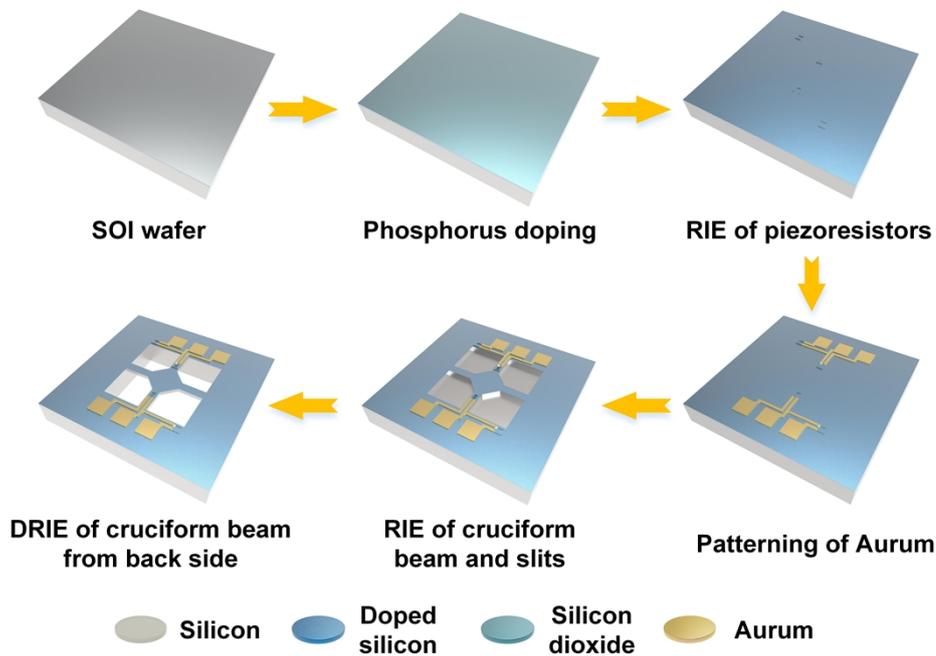
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$$Y = 0.36148x^2 - 0.04482 \tag{12}$$

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1 **Supporting information S7:**

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4 **Figure S5.** The fabrication process of BSBA.

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6 The proposed BSBA was fabricated using a MEMS manufacturing process as shown  
7 in Fig. S5. A p-type Silicon-On-Insulator (SOI) wafer with a device Si layer thickness  
8 of 0.3  $\mu\text{m}$ , an isolation  $\text{SiO}_2$  layer of 1  $\mu\text{m}$ , and a handle Si layer of 450  $\mu\text{m}$  was selected  
9 as the substrate. The top device layer was doped with n-type phosphorus and thermally  
10 annealed for activation. The piezoresistor was etched into a U-shaped pattern with a  
11 sheet resistance of 300  $\Omega$  per square. Next, aurum thin film with a thickness of 0.5  $\mu\text{m}$   
12 was sputtered and patterned to create wires connected to the piezoresistors completing  
13 a circuit. The enlarged center and CTS structures were fabricated by etching the device  
14 layer and isolation layer to a depth of 50  $\mu\text{m}$  with a reactive ion etching (RIE) process.  
15 Finally, the cruciform beam was released by etching the handle layer from the backside.  
16 The completed beam was 100  $\mu\text{m}$  in width and 50  $\mu\text{m}$  thick. Six slits with circular tips  
17 were divided into two groups and distributed along one beam on the joint of the beam  
18 and center. Two piezoresistors were positioned around each slit to detect the

1 deformation of the beam, with another two piezoresistors distributed on the base. The  
2 four piezoresistors formed a Wheatstone bridge configuration. The Wheatstone bridge  
3 was powered by a 5V DC supply, and voltage change in the circuit indicated the  
4 deformation of the cruciform beam. To enable BSBA to detect bi-directional airflow, a  
5 hole with a diameter of 1 mm was carved at the corresponding position on the PCB  
6 board.

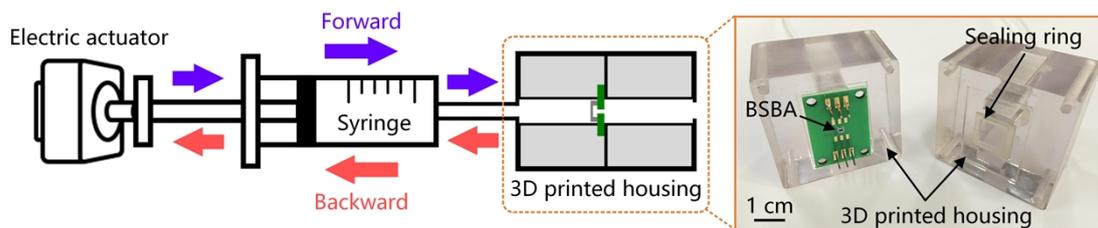
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### 10 Supporting information S8:

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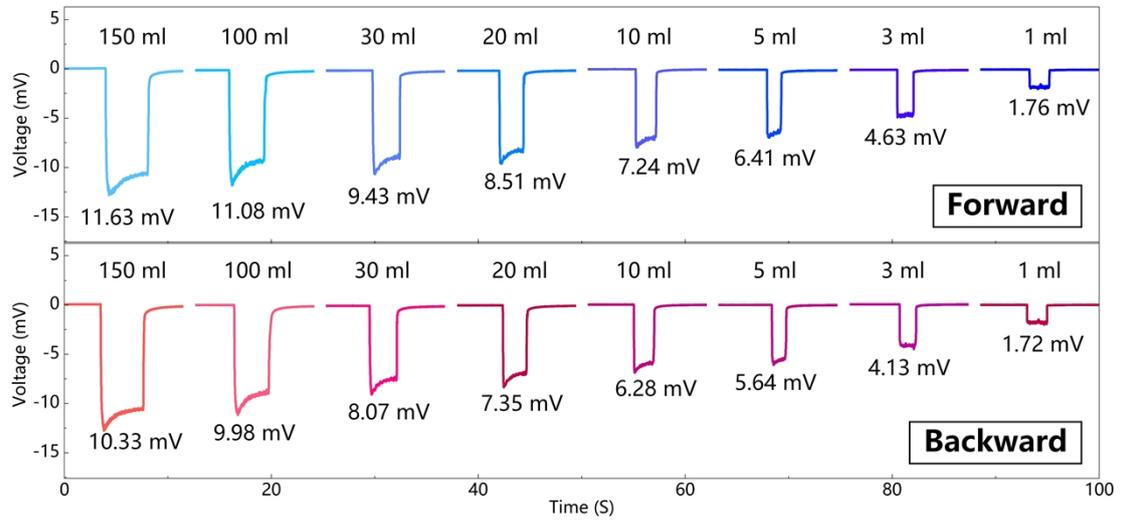
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13 **Figure S6.** Illumination of BSBA detecting different airflow volumes.

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1 **Supporting information S9:**

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4 **Figure S7.** BSBA detecting eight decreasing airflow volumes of 150 ml to 1 ml from

5 forward and backward.

1 **Supporting information S10:**

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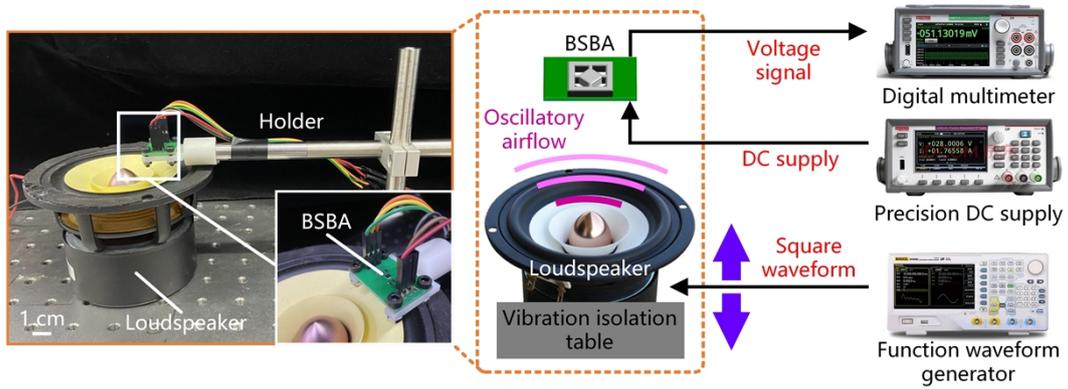
3 **Table S2.** The performance comparison of BSBA with other MEMS piezoresistive  
4 flow sensors.

Sensing unit	Quantity	Sensitivity	Sensing range	Response time	Bi-directional capability
Microcantilever with an enlarged free end <sup>1</sup>	1	0.0284 Ω/m/s	0-45 m/s	530 ms	No
Microcantilever with a corrugated structure <sup>2</sup>	1	1.157×10 <sup>-2</sup> /m/s (ΔR/R)	0.2-1 m/s	3.72 s	No
Microcantilever with focused-ion-beam <sup>3</sup>	1	3.22×10 <sup>-5</sup> /m/s (ΔR/R)	0-4 m/s	No data	No
Microcantilever <sup>4</sup>	1	5.5×10 <sup>-4</sup> /m/s (ΔR/R)	2-20 m/s	No data	No
Curved microcantilevers <sup>5</sup>	2	40 μV/m/s (±10-20 m/s) 80 μV/m/s (±20-32 m/s);	±10-32 m/s	No data	Yes
Curved microcantilevers <sup>6</sup>	4	60.35 mV/m/s (≥38.5m/s)	0-±40.5 m/s	No data	Yes
<b>BSBA (this study)</b>	<b>1</b>	<b>1.36 mV/m/s</b> (0-±2m/s) <b>0.53 mV/m/s</b> (±2-5m/s)	<b>0-±5 m/s</b>	<b>24.1 ms</b>	<b>Yes</b>

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1 **Supporting information S11:**

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4 **Figure S8.** Illustration of BSBA detecting oscillatory airflow produced by a  
5 loudspeaker.

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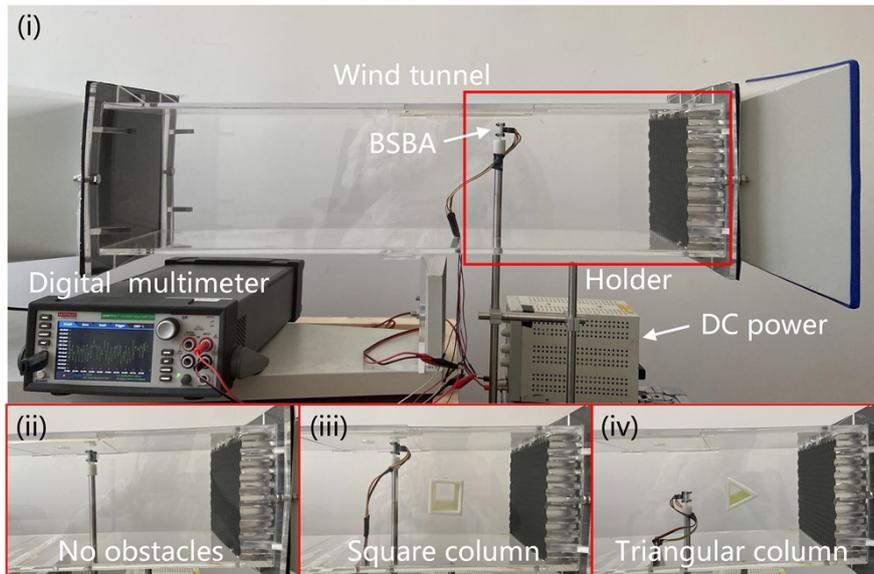
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10 **Supporting information S12:**

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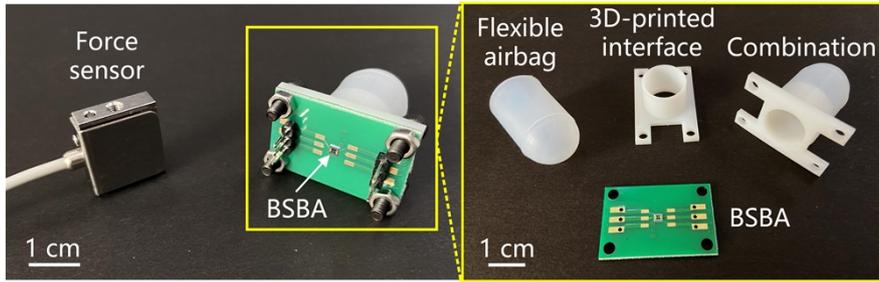
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13 **Figure S9.** Images of BSBA detecting flow field change caused by the square column  
14 and triangular column compared to without obstacles within the wind tunnel.

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1 **Supporting information S13:**

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4 **Figure S10.** The images of the force sensing module of the BSBA.

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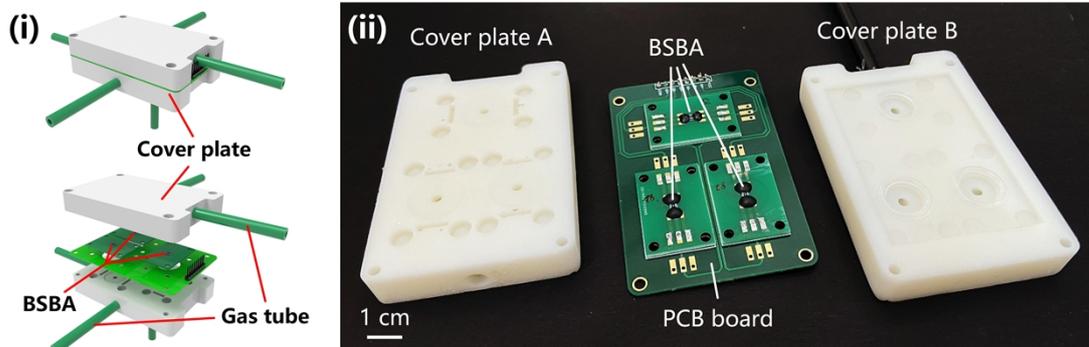
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10 **Supporting information S14:**

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13 **Figure S11.** The components of the BSBA sensor package.

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## 1 **Supporting information S15:**

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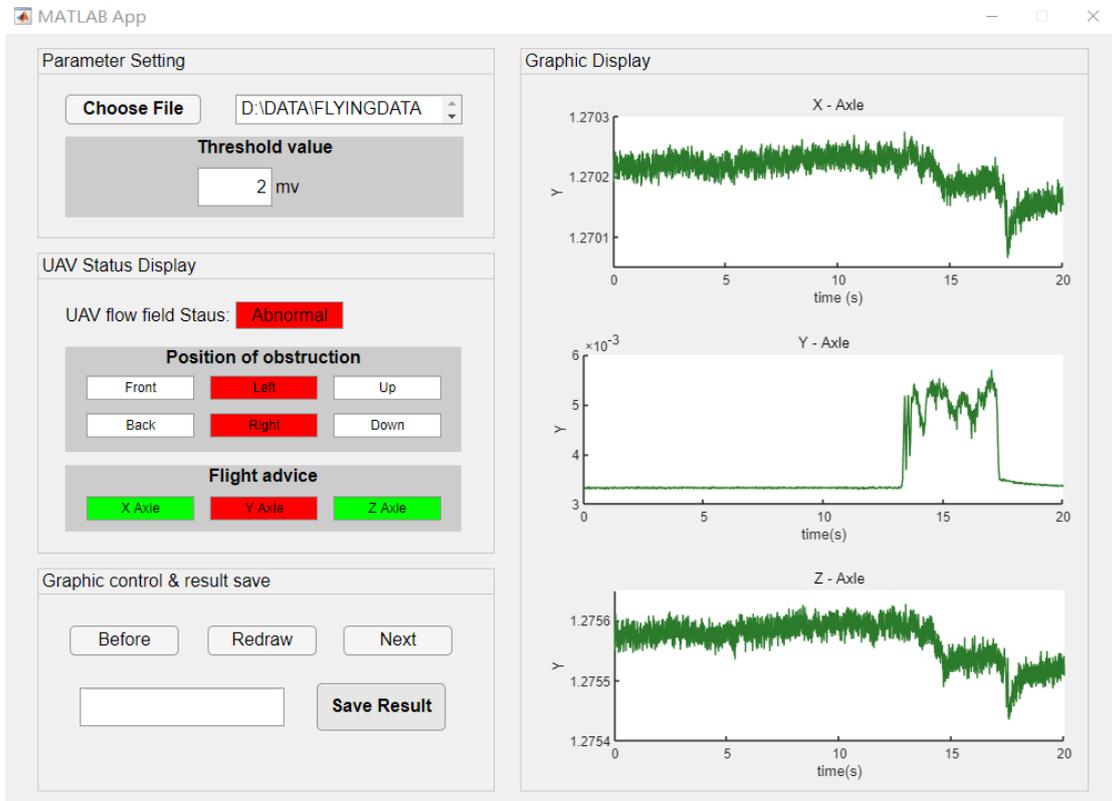
3 The obstacle detection system consists of three parts: the quadrotor, sensor package,  
4 and software. The  $370 \times 370 \times 240$  mm<sup>3</sup> quadrotor (DJI F450) was securely mounted on  
5 the platform to prevent any unintended movement. The quadrotor was equipped with  
6 9450 self-locking propellers actuated by 2312KV800 brushless motors which generated  
7 downwash airflow. The presence of an approaching obstacle affects the flow field  
8 around the quadrotor; these variations were detected by the sensor package attached to  
9 the bottom of the quadrotor's center. The sensor package consists of three BSBA  
10 sensors attached on a PCB board by soldering, 3D printed housing with internal air  
11 paths 3 mm in diameter, and 35 cm PVC tubes of 3 mm inner diameter and 6 mm outer  
12 diameter connecting the sensor to the quadrotor. The up and down tubes were made  
13 from flexible hoses and the front, back, left, and right tubes were rigid. The flow field  
14 information captured by BSBA was transmitted to the computer via a multichannel  
15 wireless data acquisition module (VKinging Electronics, VK701W, China) using a Wi-  
16 Fi communication link. The sampling frequency of the acquisition module is 480 Hz.  
17 The obstacle detection software processed the received flow field information and  
18 determined the position of the detected obstacle.

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1 **Supporting information S16:**

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4 **Figure S12.** The operation interface of quadrotor-based obstacle detection software.

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## 1 **References**

2

3 1 Y. H. Wang, C. Y. Lee and C. M. Chiang, *Sensors*, 2007, **7**, 2389–2401.

4 2 D. K. Choi and S. H. Lee, *Microelectron. Eng.*, 2012, **98**, 477–482.

5 3 D. K. Choi and S. H. Lee, *Integr. Ferroelectr.*, 2014, **157**, 157–167.

6 4 H. Takahashi, A. Nakai and I. Shimoyama, *Sensors Actuators, A Phys.*, 2018,  
7 **281**, 243–249.

8 5 C. Abels, A. Quattieri, T. Lober, A. Mariotti, L. D. Chambers, M. De Vittorio,  
9 W. M. Megill and F. Rizzi, *Beilstein J. Nanotechnol.*, 2019, **10**, 32–46.

10 6 D. Shen, Y. Jiang, Z. Ma, P. Zhao, Z. Gong, Z. Dong and D. Zhang, *J. Bionic*  
11 *Eng.*, 2022, **19**, 73–82.

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